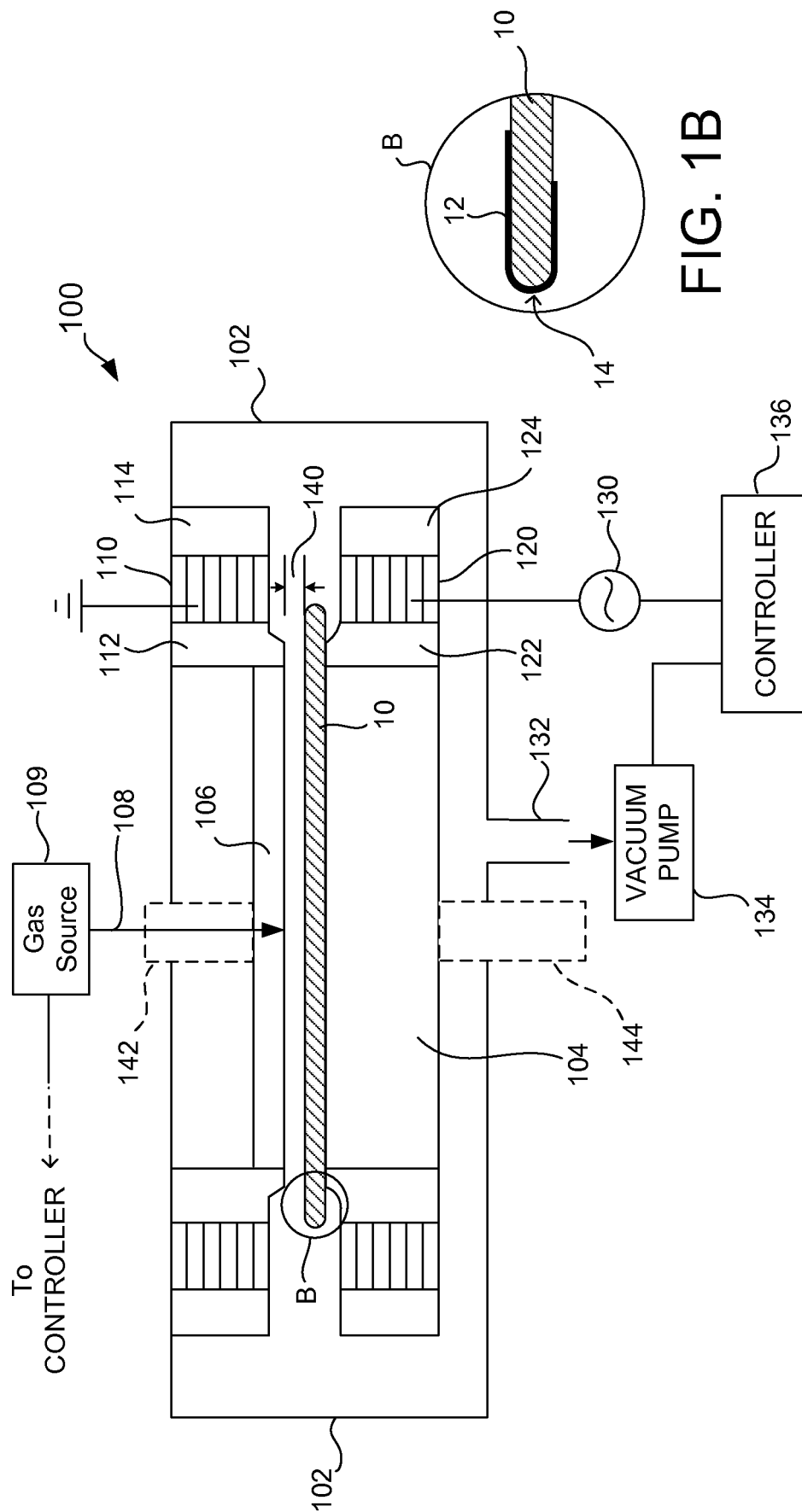




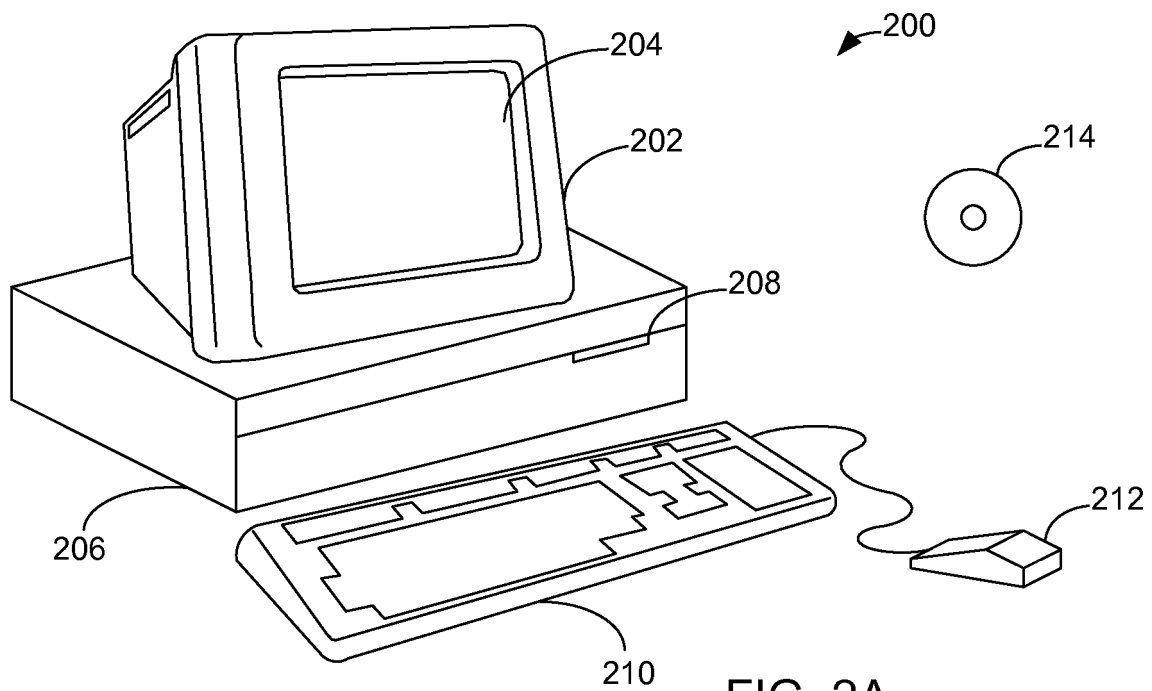


FIG. 2A

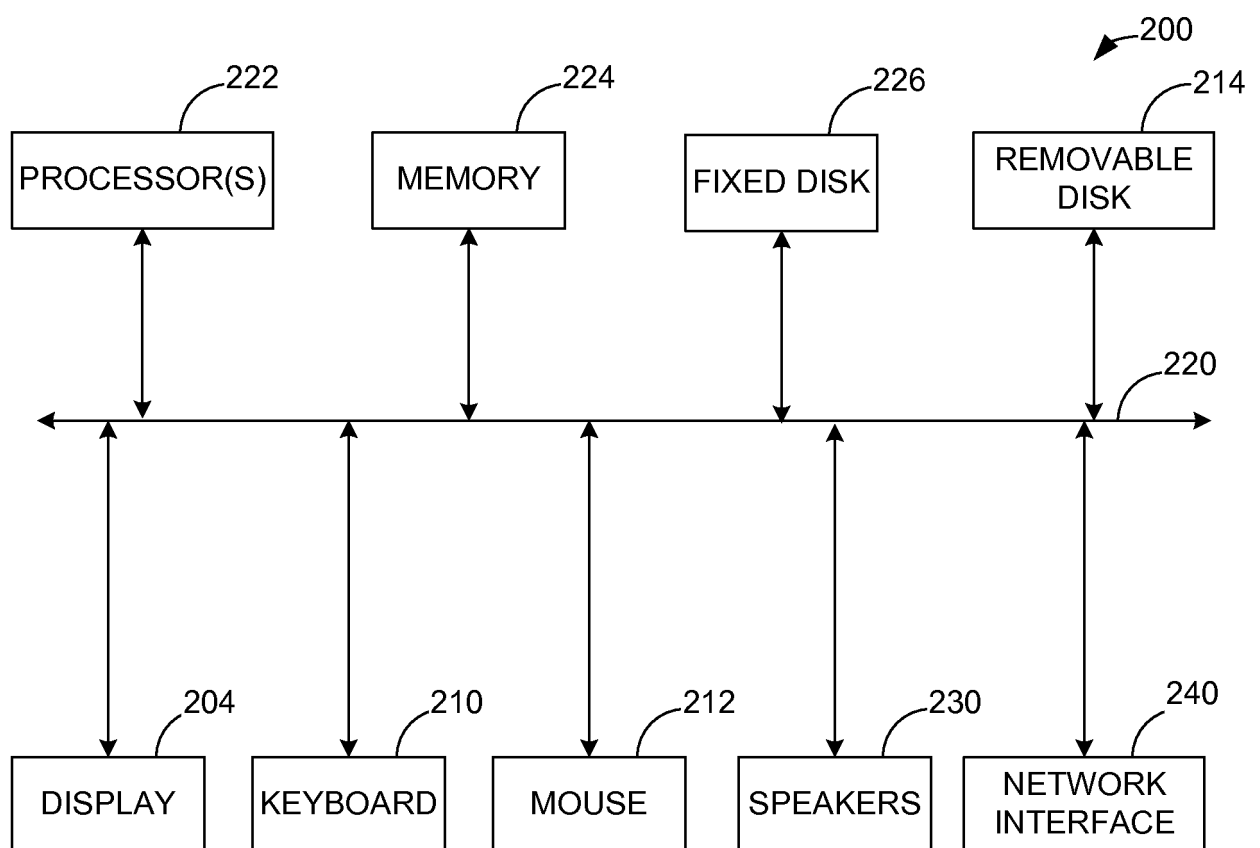


FIG. 2B

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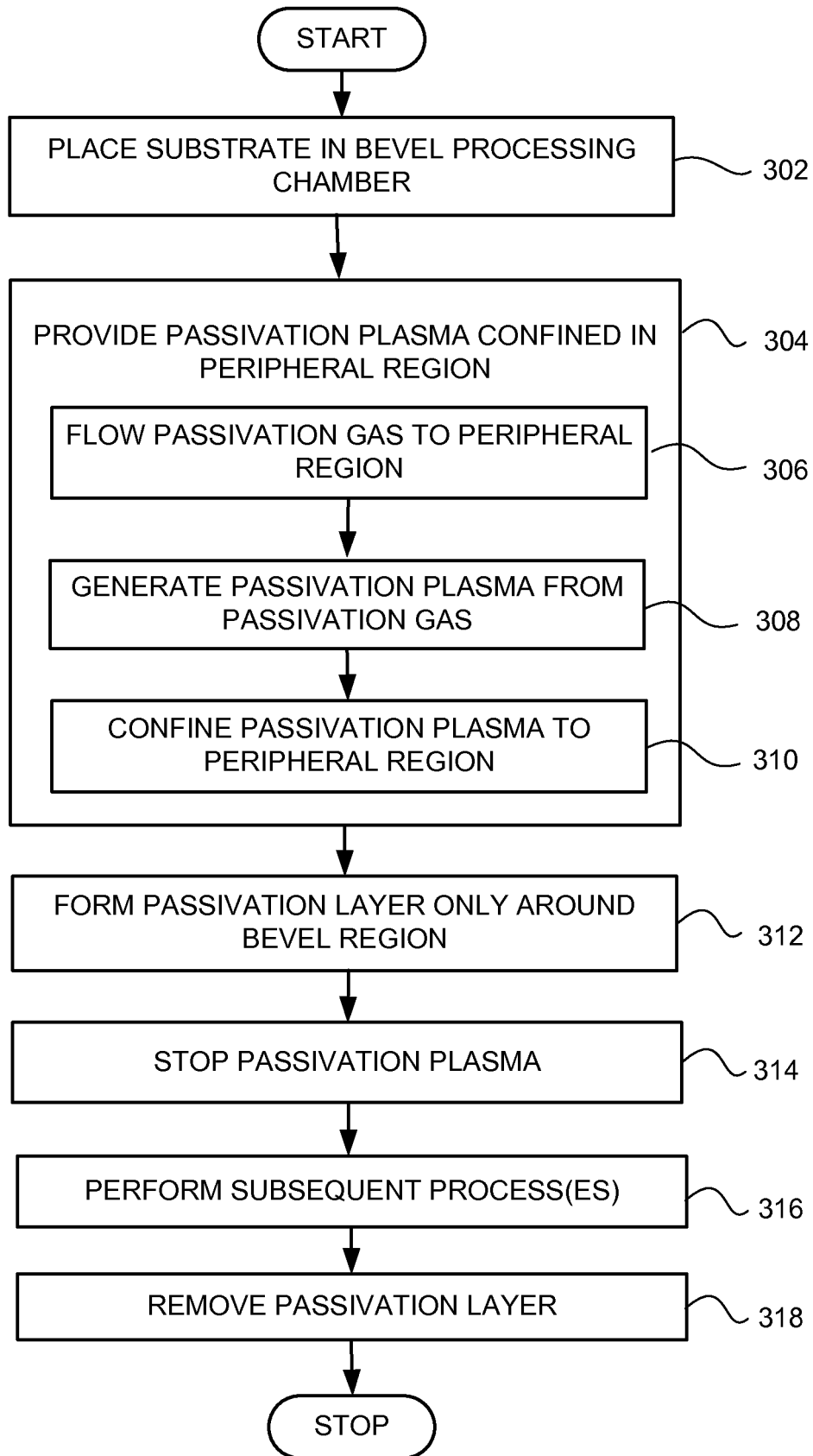


FIG. 3

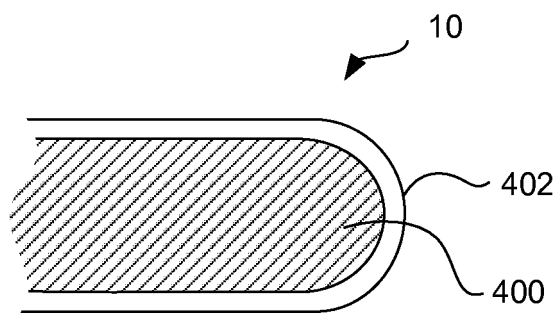


FIG. 4A

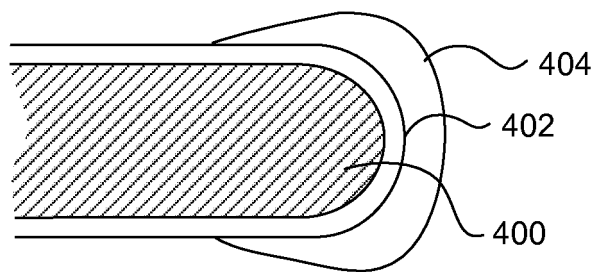


FIG. 4B

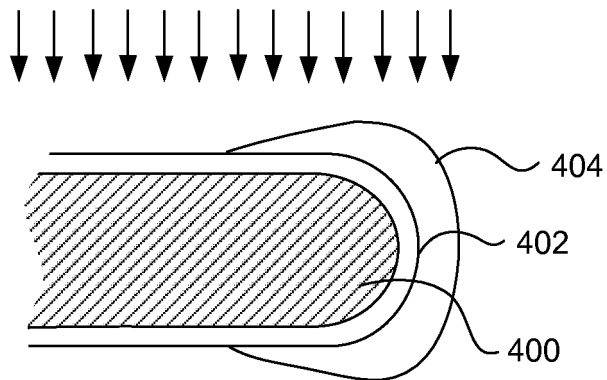


FIG. 4C

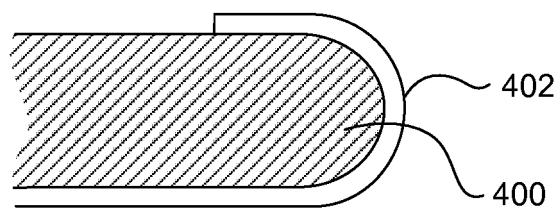


FIG. 4D

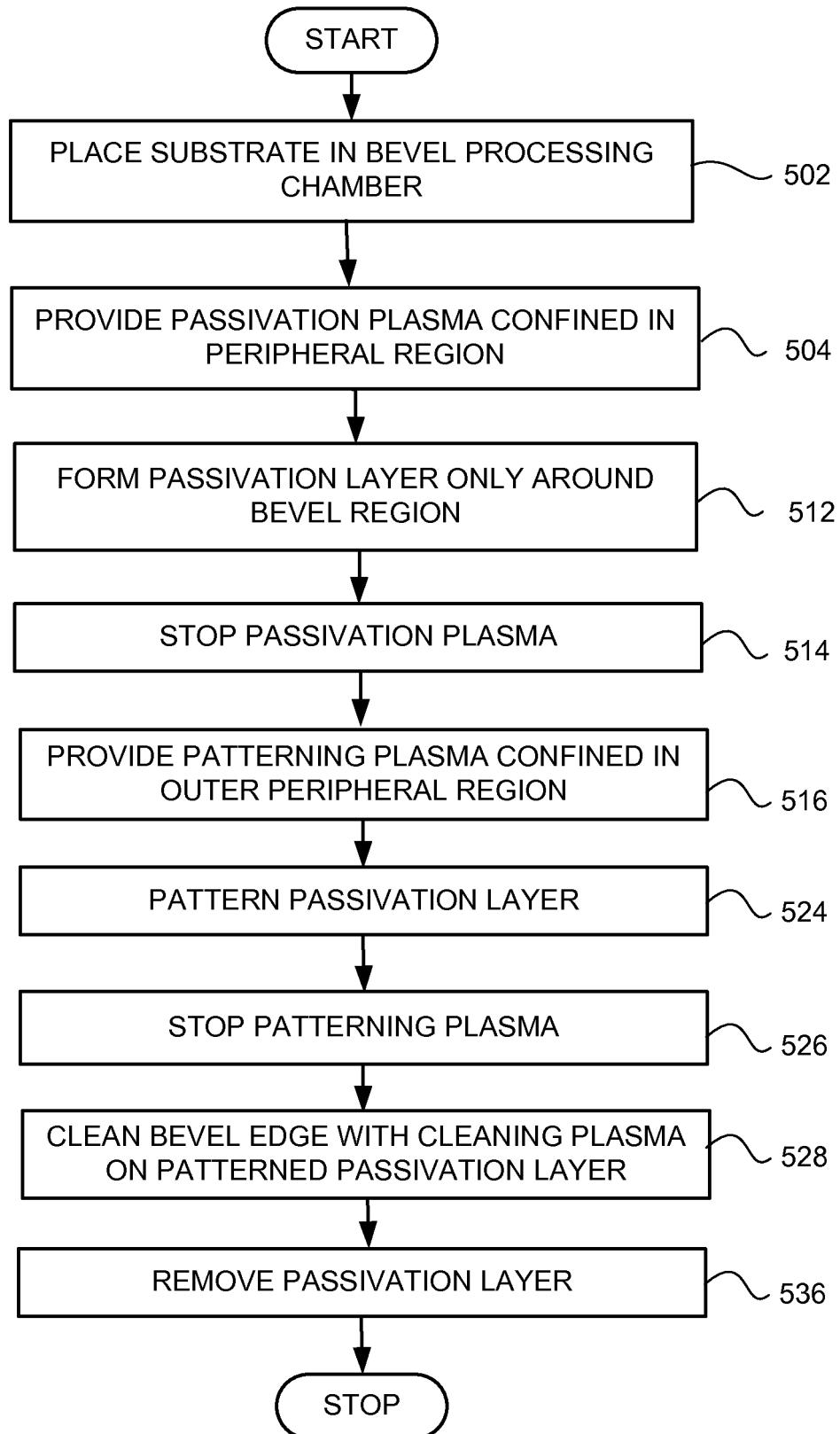


FIG. 5A

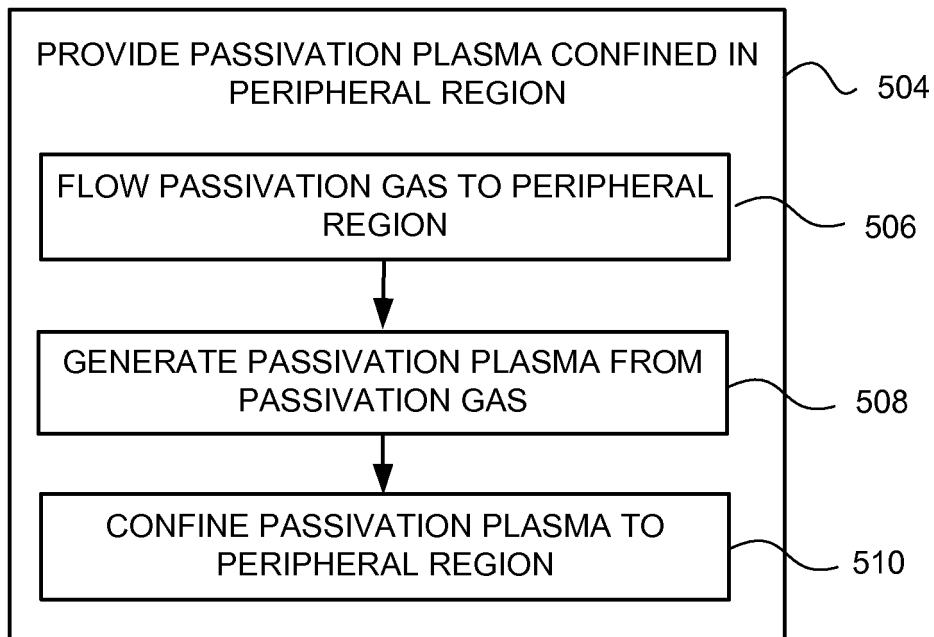


FIG. 5B

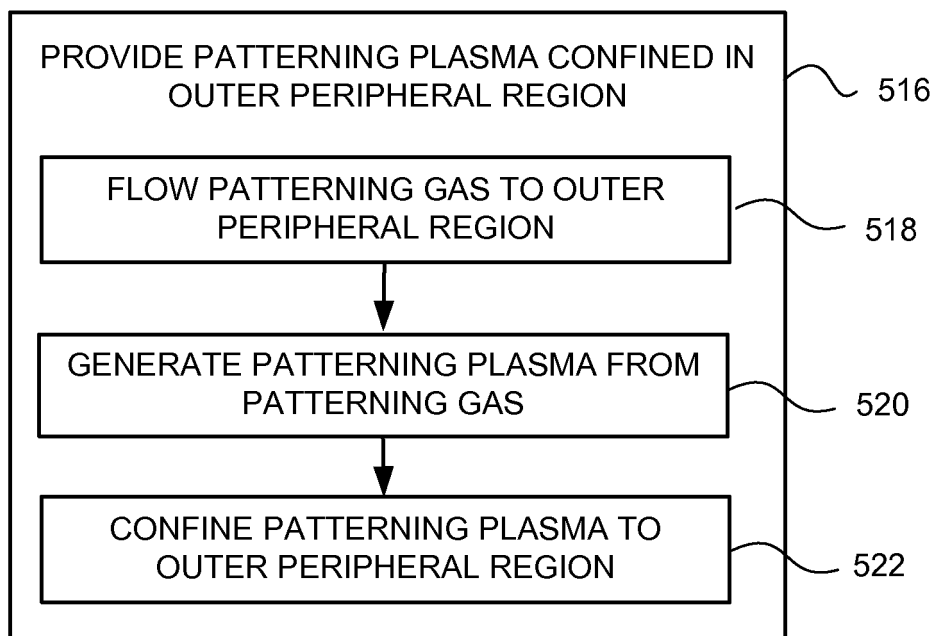


FIG. 5C

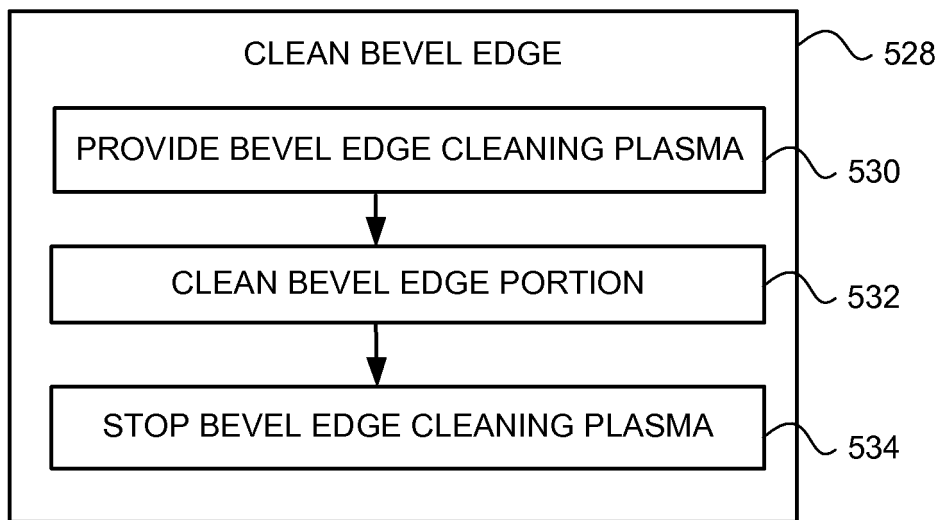


FIG. 5D

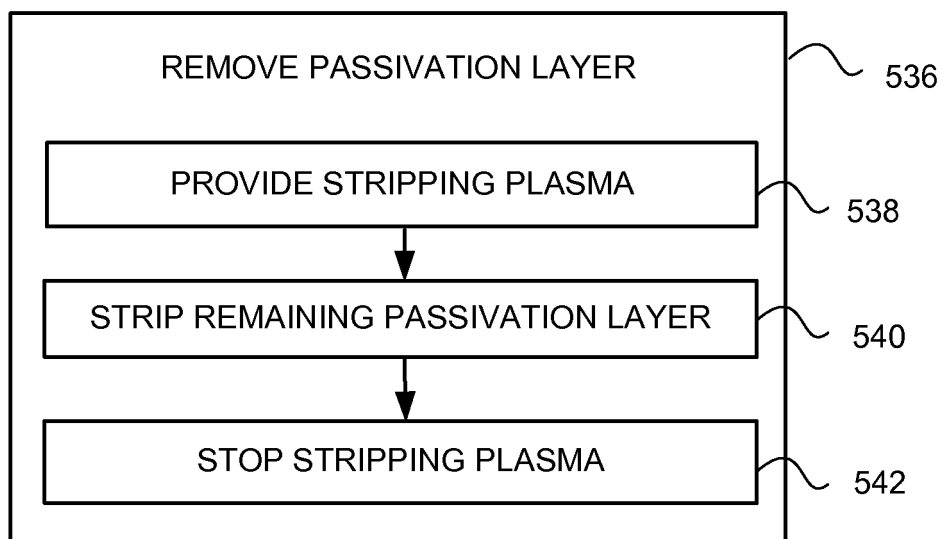
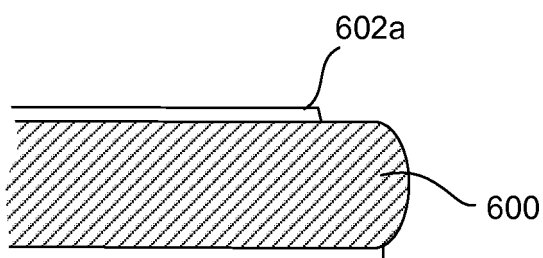
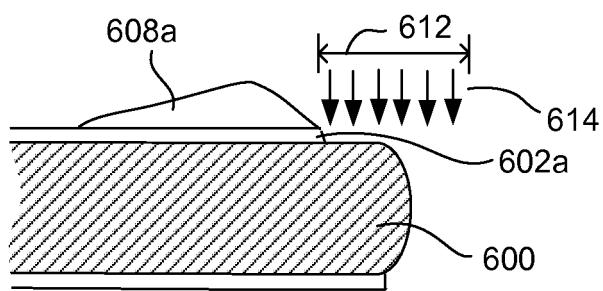
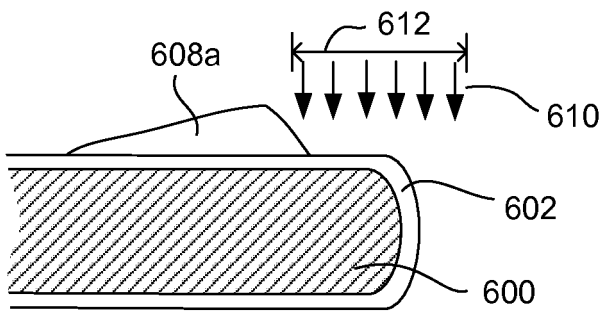
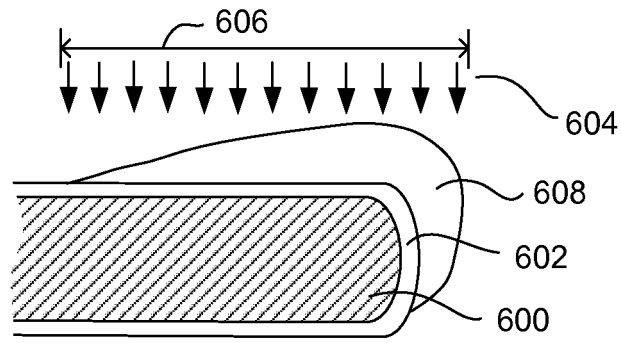
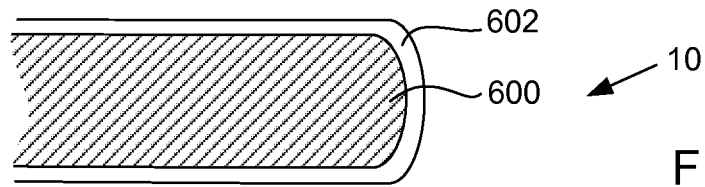


FIG. 5E



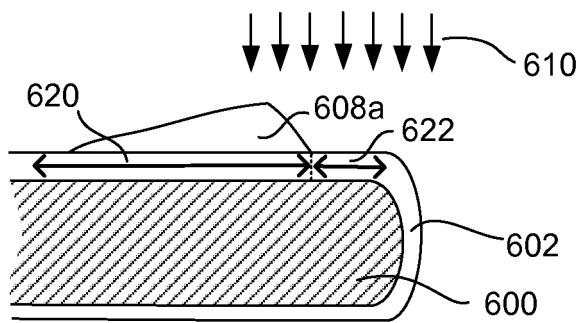


FIG. 6F

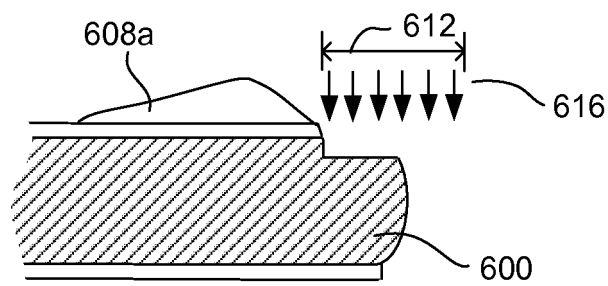


FIG. 6G

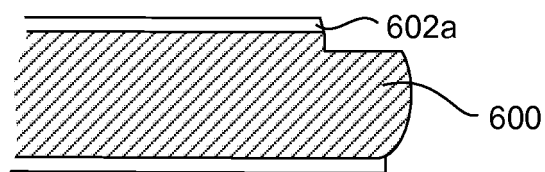


FIG. 6H

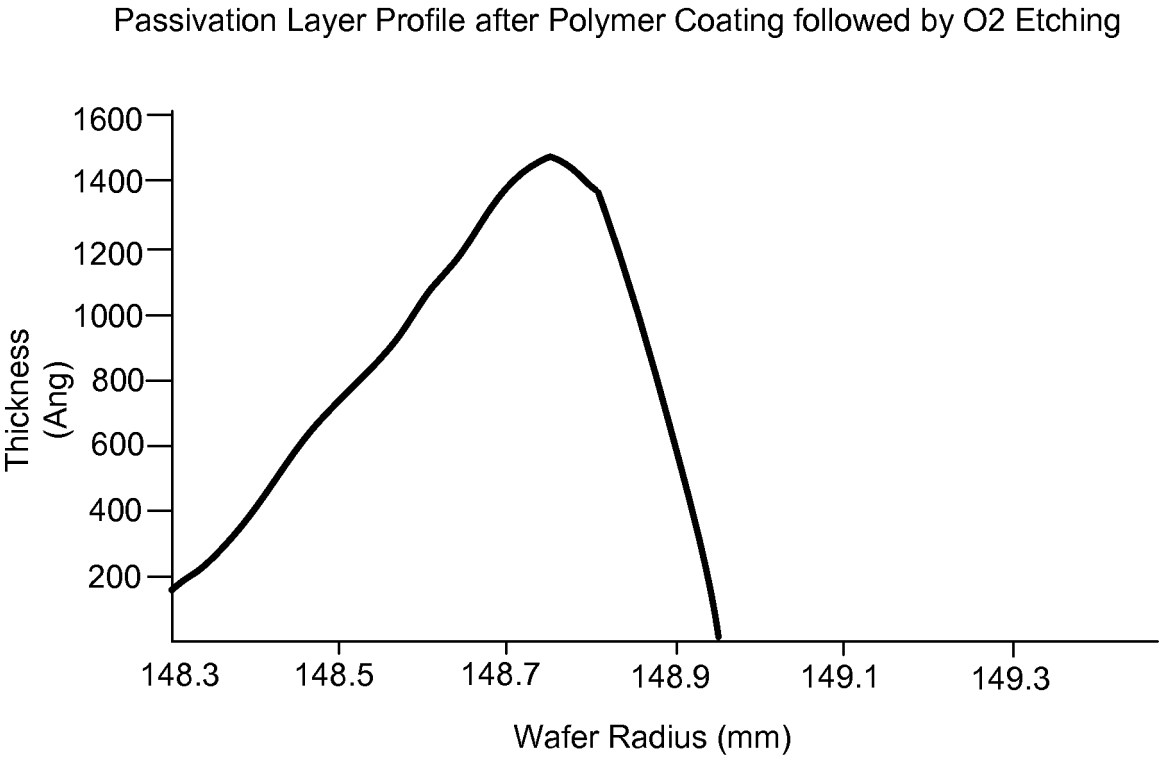


FIG. 7

Oxide Layer Profile with Conventional Plasma Bevel Clean

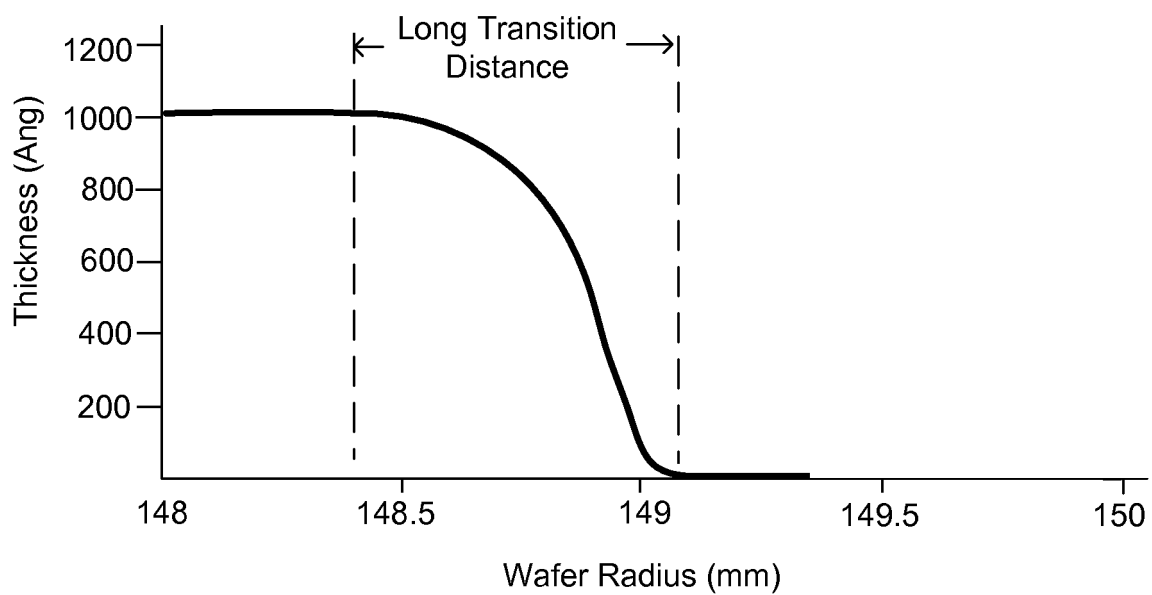


FIG. 8A

Oxide Layer Profile with In Situ Bevel Passivation and Clean

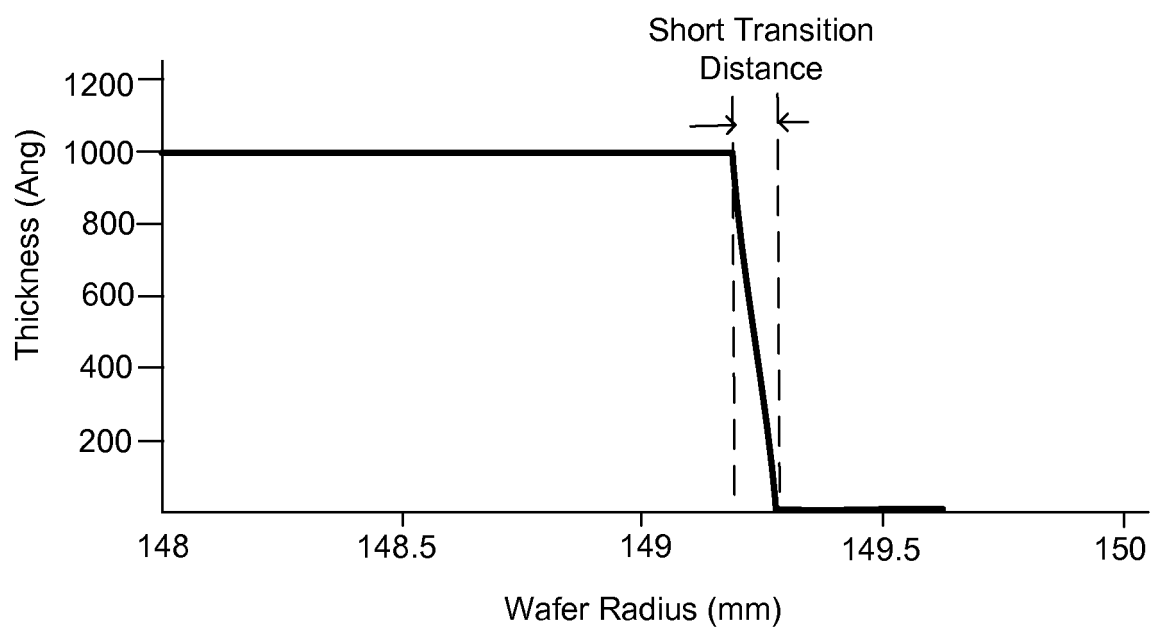


FIG. 8B

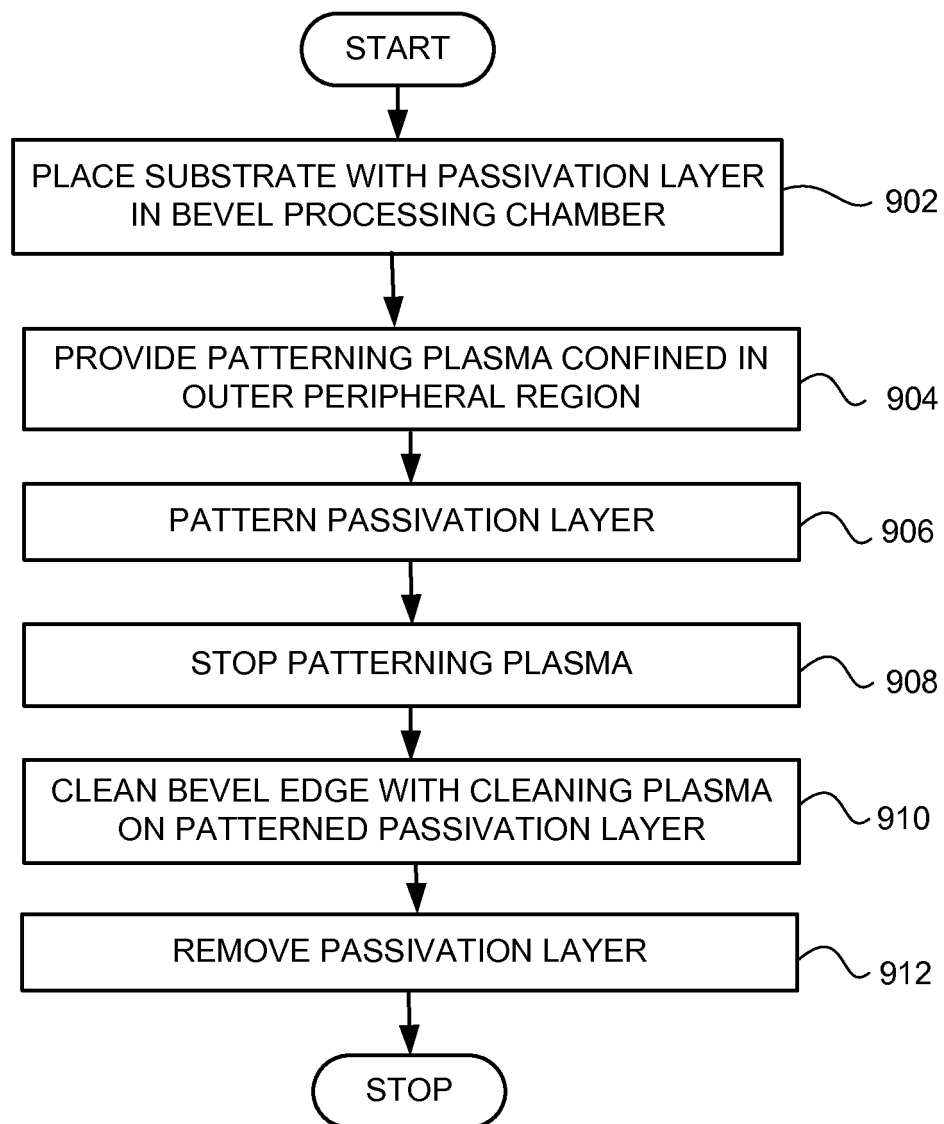


FIG. 9

